



ASMT.055AUS

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Timmermans et al.
Appl. No. : 10/690,215
Filed : October 20, 2003
For : METHOD FOR THE
DEPOSITION OF A REACTION
CHAMBER FOR THE
DEPOSITION OF SILICON
NITRIDE FILMS
Examiner : Unknown

Group Art Unit 2812

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February 6, 2004

(Date)

Eli A. Loots, Reg. No. 54,715

REQUEST FOR CORRECTED FILING RECEIPT

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P.O. Box 1450
Office of Initial Patent Examination
Customer Service Center
Alexandria, VA 22313-1450

Dear Sir:

Applicants hereby request that the Official Filing Receipt, a copy of which is enclosed, be corrected to reflect the true filing date of October 20, 2003. Presently, the Filing Receipt incorrectly shows the filing date as October 21, 2003. Enclosed herewith are copies of the Certificate of Mailing by Express Mail and the Express Mail address label, both reflecting that

Appl. No. : 10/690,215
Filed : October 20, 2003

the application was filed on October 20, 2003.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 2/6/04

By: 

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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/690,215	10/21/2003	2812	0.00	ASMINT.055AUS	1	20	5

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20995
KNOBBE MARTENS OLSON & BEAR LLP
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FOURTEENTH FLOOR
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CONFIRMATION NO. 2345

FILING RECEIPT



OC000000011726065

Date Mailed: 01/21/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Eric A.H. Timmermans, Residence Not Provided;
Maarten J. Teepe, Residence Not Provided;
Raffaele Mucciato, Residence Not Provided;
Rudi Wilhelm, Residence Not Provided;

Domestic Priority data as claimed by applicant

Foreign Applications

If Required, Foreign Filing License Granted: 01/20/2004

Projected Publication Date: To Be Determined - pending completion of Missing Parts

Non-Publication Request: No

Early Publication Request: No

Title

Method for the deposition of a reaction chamber for the deposition of silicon nitride films

Preliminary Class

438

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Title 35, United States Code, Section 184
Title 37, Code of Federal Regulations, 5.11 & 5.15**

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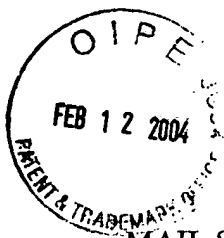
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MAIL STOP PATENT APPLICATION

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CERTIFICATE OF MAILING BY "EXPRESS MAIL"

Attorney Docket No. : ASMINT.055AUS

Applicant(s) : TIMMERMANS et al.

For : METHOD FOR THE DEPOSITION OF A
REACTION CHAMBER FOR THE
DEPOSITION OF SILICON NITRIDE FILMS

Attorney : Adeel S. Akhtar

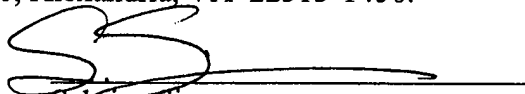
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Date of Deposit : October 20, 2003

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Transmittal letter; specification in 13 pages; 1 sheets of drawings; filed
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Sabrina Simmons

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